

CY-086型微型压差传感器**CY-086 Micro Differential Pressure Sensor****1.工作原理**

传感器采用硅压阻效应原理，利用半导体平面工艺和硅微机械加工技术制作而成，利用真空注油技术制成的双膜片结构。信号调节器中带有滤波器。

2.特点

具有双面耐腐蚀、滤波器衰减高、传感器体积小等特点。

3.应用范围

广泛应用于航天、航空以及各类自控系统中。

1.Working Principle:

Working Principle of sensor is silicon piezoresistive effect. It is fabricated with semiconductor planar technology and silicon micromachining technology in double diaphragm structure adopting vacuum oil injection technology. There is filter in signal conditioner.

2. Characteristic:

Double sided anti-corrosion, high filter attenuation, and small volume.

3. Application:

It is widely used in aerospace, aviation, and all kinds of automatic control system.



图 Picture CY-086



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